L Number	Hits	Search Text	DB	Time stamp
1	58		USPAT;	2004/01/12 08:23
		layer)	US-PGPUB;	
ļ			EPO; JPO;	
	l.		DERWENT;	i
	ŀ		IBM_TDB	
2	36	(USPAT;	2004/01/12 08:23
		layer)	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
3	389	MEMS and etch\$3 and (sacrificial).clm.	IBM TDB	0004/01/10 00 10
١	307	MENS and ecchys and (sacrificial).cim.	USPAT; US-PGPUB;	2004/01/12 09:10
			EPO; JPO;	
			DERWENT;	
1			IBM TDB	
-	761	(216/2).CCLS.	USPAT;	2003/12/03 12:23
			US-PGPUB;	2000, 22, 00 22, 20
			EPO; JPO;	
	i		DERWENT;	
			IBM_TDB	
-	87	((216/2).CCLS.) and (Ge or Germanium)	USPAT;	2004/01/11 17:35
ĺ	1		US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
_	4290	(MEMS or micromechanical or	IBM_TDB USPAT;	2002/10/12 12:00
	12,00	microelectromechanical or	US-PGPUB;	2003/12/13 13:09
		microstructure\$1) and (Ge or Germanium)	EPO; JPO;	
	ł	mississing of the of occident and	DERWENT;	
			IBM TDB	
-	2	((MEMS or micromechanical or	USPAT;	2003/12/03 12:39
		microelectromechanical or	US-PGPUB;]
		microstructure\$1) and (Ge or	EPO; JPO;	1
		Germanium)).ti.	DERWENT;	
_	116	//MEMS	IBM_TDB	
_	113	((MEMS or micromechanical or microelectromechanical or	USPAT;	2003/12/03 12:25
		microstructure\$1) and (Ge or	US-PGPUB; EPO; JPO;	
		Germanium)).clm.	DERWENT;	
			IBM TDB	
-	179	(((MEMS or micromechanical or	USPAT;	2003/12/03 12:26
		microelectromechanical or	US-PGPUB;	
		microstructure\$1) and (Ge or	EPO; JPO;	i
		Germanium)).ab.) or (((MEMS or	DERWENT;	
		micromechanical or microelectromechanical	IBM_TDB	
		or microstructure\$1) and (Ge or		[
		Germanium)).ti.) or (((MEMS or		
		micromechanical or microelectromechanical or microstructure\$1) and (Ge or		
		Germanium)).clm.)		
- 1	22	(MEMS or micromechanical or	USPAT;	2003/12/03 12:33
		microelectromechanical or	US-PGPUB:	2003/12/03 12.33
l		microstructure\$1) and ((Ge or Germanium)	EPO; JPO;	
l		same (protect\$3 adj (coating or layer or	DERWENT;	
-		material or film)))	IBM TDB	
-	23	(MEMS or micromechanical or	USPAT;	2003/12/03 12:34
}		microelectromechanical or	US-PGPUB;	
ļ		microstructure\$1) and ((Ge or Germanium)	EPO; JPO;	
		and (protect\$3 adj (coating or layer or	DERWENT;	
_	23	material or film))).clm. (MEMS or micromechanical or	IBM_TDB	0000/10/00 10
	23	microelectromechanical or	USPAT;	2003/12/03 12:43
	1	microstructure\$1).ab. and (Ge or	US-PGPUB;	
		Germanium) and (protect\$3 adj (coating or	EPO; JPO; DERWENT;	
		layer or material or film)).ab.	IBM TDB	
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material or film]).clm,) or (NEMS or micromechanical or microsetructure\$1) and (Ge or Germanium) and (protects3 adj (coating or lawer);					
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Germanium) .ab. DERWENT; IBM TDB USPAT; Coating or layer or material or removable and (protect\$3 adj (coating or layer or material or removable) and (protect\$3 adj (coating or layer or material or removable) and (protect\$3 adj (coating or layer or material or film)) .ab. Evolution of material or film) And (protect\$3 adj (coating or layer or material or film) And (protect\$3 adj (coating or layer or material or film)) and (protect\$3 adj (coating or layer or material or film)) and (protect\$3 adj (coating or layer or material or film)) and (protect\$3 adj (coating or layer or material or film)) And (polysilicon or nucleat\$3) adj layer) USPAT; USPAGUBNIT; IBM TDB (USPAT; USPAGUBN) USPAT; USPAGUBNIT; IBM TDB (USPAT; USPAGUBN) USPAT; USPAGUBNIT; IBM TDB (USPAT; USPAGUBN) USPAT; USPAGUBNIT; IBM TDB (USPAGUBN) USPAGUBND					
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Coating or layer or material or film)) ab.	_	0.60	//Co on Commonium) and (number of 2 and		2002/10/12 12 00
Film))).ab. EEO, JPO; DERMENT; IBM TDB USPAT; USPGUB; EEO, JPO; DERMENT;] 300			2003/12/13 13:09
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3 ((Ge or Germanium) and (temporary or removable) and (protect\$3 adj (coating or layer or material or film)) ab. 14 ((216/2).CCLS.) and (Ge or Germanium) and (protect\$3 adj (coating or layer or material or film)) 15 ((216/2).CCLS.) and (Ge or Germanium) and (protect\$3 adj (coating or layer or material or film)) 18 ((18			Lizzani, i i i i i i i i i i i i i i i i i i		
Cleg or Germanium) and (temporary or removable) and (protect\$3 adj (coating or layer or material or film)) ab.					
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layer or material or film)) a.b. Continue	1				
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10	1	1	· ·		į į
(coating or layer or material or film))).ab. and polysilicon ((Ge or Germanium) and (protect\$3 adj (coating or layer or material or film))).ab. and (MEMS or micromechanical or microstructure\$1) 113 ((Ge or Germanium) and (protect\$3 adj (coating or layer or material or film))) and (front adj side) and (back adj side) ((MEMS or micromechanical or microstructure\$1) ((MEMS or micromechanical or microstructure\$1) ((MEMS or micromechanical or microstructure\$1) ab. and ((Ge or Germanium) and (protect\$3 adj (coating or layer or material or film))) and (front adj side) and (back adj side) ((MEMS or micromechanical or microstructure\$1).ab. and ((Ge or Germanium) adj layer) (US-PGPUB; EPC; JPO; DERWENT; DERWENT; DERWENT; DERWENT;	-	10	((Ge or Germanium) and /nrotocts3 add		2002/12/05 12:27
film))) ab. and polysilicon ((Ge or Germanium) and (protect\$3 adj (coating or layer or material or film))) ab. and (MEMS or micromechanical or microstructure\$1) ((Ge or Germanium) and (protect\$3 adj (protect\$3 adj (coating or layer or material or film))) abscription and (front adj side) and (back adj side) ((Ge or Germanium) and (protect\$3 adj (coating or layer or material or film))) and (front adj side) and (back adj side) ((MEMS or micromechanical or microelectromechanical or microelectromechanical or microelectromechanical or microelectromechanical or microstructure\$1) ab. and ((Ge or Germanium) adj layer) (DERWENT;	1	10			2003/12/03 12:3/
- 3 ((Ge or Germanium) and (protect\$3 adj (USPAT; (Coating or layer or material or film))).ab. and (MEMS or micromechanical or microstructure\$1) - 113 ((Ge or Germanium) and (protect\$3 adj (Coating or layer or material or film))) and (front adj side) and (back adj side) - 8 (MEMS or micromechanical or microstructure\$1) ab. and ((Ge or Germanium) and (Ge or Germanium) and (Drotect\$3 adj (USPAT; USPEPUB; EPO; JPO; DERWENT; IBM TDB (USPAT; USPEPUB; EPO; JPO; DERWENT; EM TDB (USPAT; USPEPUB; EPO; JPO; DERWENT; EM TDB (USPAT; USPEPUB; EPO; JPO; DERWENT; EPO; JPO; DERWENT; EPO; JPO; DERWENT; EPO; JPO; DERWENT;					
Code of Germanium and (protect\$3 adj (coating or layer or material or film)) ab. and (MEMS or micromechanical or microstructure\$1) Code of Germanium and (protect\$3 adj (coating or layer or material or film)) and (front adj side) and (back adj side) DERWENT; DERWENT; LIM TDB (USPĀT; US-PGPUB; and (front adj side) and (back adj side) DERWENT; LIM TDB (USPĀT; US-PGPUB; and core microstructure\$1) ab. and ((Ge or Germanium) adj layer) DERWENT; DERWENT; Composition Compos			Fragrands		
3					
Coating or layer or material or film)) ab. and (MEMS or micromechanical or microstructure\$1) 113 ((Ge or Germanium) and (protect\$3 adj (coating or layer or material or film)) US-PGPUB; and (front adj side) and (back adj side) US-PGPUB; and (front adj side) and (back adj side) US-PGPUB; and (front adj side) US-PGPUB; and (MEMS or micromechanical or microelectromechanical or microelectromechanical or microstructure\$1).ab. and ((Ge or Germanium) adj layer) US-PGPUB; EPO; JPO; DERWENT; 2003/12/05 12:47 US-PGPUB; EPO; JPO; DERWENT; US-PGPUB; EPO; JPO; JPO; DERWENT; US-PGPUB; EPO; JPO; JPO; JPO; JPO; JPO; JPO; JPO; J	-	3	((Ge or Germanium) and (protect\$3 adj		2003/12/03 13:28
or microelectromechanical or microstructure\$1) 113 ((Ge or Germanium) and (protect\$3 adj (USPAT; (Coating or layer or material or film))) and (front adj side) and (back adj side) - 8 (MEMS or micromechanical or microelectromechanical or microelectromechanical or microstructure\$1).ab. and ((Ge or Germanium) adj layer) - BERWENT; IBM TDB (USPAT; USP-GFUB; EPO; JPO; DERWENT; EM TDB (USPAT; USP-GFUB; EPO; JPO; DERWENT; EPO; JPO; DERWENT; EPO; JPO; DERWENT;			(coating or layer or material or	US-PGPUB;	
microstructure\$1) ((Ge or Germanium) and (protect\$3 adj (OspFār; (Coating or layer or material or film))) and (front adj side) and (back adj side) (DERWENT; and (front adj side) and (back adj side) (MEMS or micromechanical or microelectromechanical or microelectromechanical or microstructure\$1).ab. and ((Ge or Germanium) adj layer) (Germanium) adj layer)					
- 113 ((Ge or Germanium) and (protect\$3 adj (coating or layer or material or film))) and (front adj side) and (back adj side) EPO; JPO; DERWENT; IBM TDB USPĀT; USPGUB; EVO; JPO; DERWENT; IBM TDB USPĀT; USPGUB; EPO; JPO; DERWENT; EFO; JPO; DERWENT; EFO; JPO; DERWENT; EFO; JPO; DERWENT; EFO; JPO; DERWENT;					
Coating or layer or material or film)) US-DEPUB; and (front adj side) and (back adj side) EPO; JPO; DERWENT; IBM TDB USPĀT; USPĀT; Microelectromechanical or Microelectromechanical or Microstructure\$1).ab. and ((Ge or BPO; JPO; Germanium) adj layer) DERWENT;	_	113			
and (front adj side) and (back adj side) 8 (MEMS or micromechanical or microelectromechanical or microstructure\$1).ab. and ((Ge or Germanium) adj layer) BEPO; JPO; DERWENT; 2003/12/05 12:47 US-PGPUB; EPO; JPO; DERWENT;		113	(Ge or Germanium) and (protect\$3 adj		2003/12/05 12:38
DERWENT; IBM TDB USPĀT; IBM TDB USPĀT;					
- 8 (MEMS or micromechanical or USPĀT; 2003/12/05 12:47 microelectromechanical or US-PGPUB; microstructure\$1).ab. and ((Ge or EPO; JPO; Germanium) adj layer) DERWENT;			and (rrone ad) side, and (back ad) side)		
MEMS or micromechanical or USPĀT; 2003/12/05 12:47 microelectromechanical or US-PGPUB; microstructure\$1).ab. and ((Ge or Germanium) adj layer) DERWENT;					
microelectromechanical or US-PGPUB; microstructure\$1).ab. and ((Ge or EPO; JPO; Germanium) adj layer) DERWENT;	-	8	(MEMS or micromechanical or		2003/12/05 12:47
microstructure\$1).ab. and ((Ge or EPO; JPO; Germanium) adj layer) DERWENT;			microelectromechanical or		2000/12/00 12:4/
Germanium) adj layer) DERWENT;			microstructure\$1).ab. and ((Ge or	EPO; JPO;	
		l	Germanium) adj layer)	DERWENT;	

3	81		USPAT;	2004/01/11 16:42
		microelectromechanical or	US-PGPUB;	
		microstructure\$1) and ((Ge or Germanium) adj layer)	EPO; JPO; DERWENT;	
		adj rayer)	IBM TDB	
_	2455	(MEMS or micromechanical or	USPAT;	2003/12/05 12:56
	1	microelectromechanical or	US-PGPUB;	2000, 12, 00 12,00
		microstructure\$1) and ((back adj side) or	EPO; JPO;	1
		back-side or backside)	DERWENT;	
			IBM_TDB	
-	255		USPAT;	2003/12/05 13:32
1		microelectromechanical or microstructure\$1) and ((back adj side) or	US-PGPUB;	
i		back-side or backside).clm.	EPO; JPO; DERWENT;	
	1	back bide of backbide, term.	IBM TDB	
-	7		USPĀT;	2003/12/05 13:34
		sensor).ab. and ((back adj side) or	US-PGPUB;	1
1	1	back-side or backside).clm.	EPO; JPO;	
1	1		DERWENT;	
	40	(IBM_TDB	0000/00/05 40 05
-	40		USPAT;	2003/12/05 13:36
		side) or back-side or backside).clm.	US-PGPUB; EPO; JPO;	
1			DERWENT;	
1			IBM TDB	
-	4	(inches and sembor) table and ((back ad) side)	USPAT;	2003/12/05 13:37
		or back-side or backside).clm.	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	· ·
_	10	(MEMS and sensor).ab. and etch\$3.clm.	IBM_TDB	0000/10/05 10 07
_	1	(MEMS and sensor).ab. and ecchos.cim.	USPAT; US-PGPUB;	2003/12/05 13:37
			EPO; JPO;	
	1		DERWENT;	
	İ		IBM_TDB	
-	92	(accelerometer).ab. and etch\$3.clm.	USPAT;	2003/12/05 13:37
			US-PGPUB;	
			EPO; JPO;	
	1		DERWENT; IBM TDB	
-	3	(accelerometer).ab. and ((back adj side)	USPAT;	2003/12/05 14:33
		or back-side or backside).clm.	US-PGPUB;	2000, 12, 00 11.00
	1		EPO; JPO;	
			DERWENT;	
_	2	/#6260005#\ DW	IBM_TDB	
_		("6368885").PN.	USPAT;	2003/12/05 14:08
	1		US-PGPUB; EPO; JPO;	
	1		DERWENT;	
	1		IBM TDB	
-	6	("5527744" "5903380" "6080675"	USPAT	2003/12/05 14:08
	2000	"6140689" "6204087" "6225145").PN.		
_	2889	(MEMS or micromechanical or microelectromechanical or	USPAT;	2003/12/05 14:11
		microelectromechanical or microstructure\$1) and (protect\$3 adj	US-PGPUB; EPO; JPO;	
		(coating or layer or material or film))	DERWENT;	
		. , = ==,++ += =========================	IBM TDB	
-	646	(MEMS or micromechanical or	USPAT;	2003/12/05 14:33
		microelectromechanical or	US-PGPUB;	
		microstructure\$1) and (protect\$3 adj	EPO; JPO;	
		(coating or layer or material or film))	DERWENT;	
_	60	and sensor (diaphram and cavity).clm.	IBM_TDB USPAT;	2003/12/05 14:33
	"	(azapizam ana cavicy) (cin.	US-PGPUB;	2003/12/05 14:33
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	141	(transducer\$1).ab. and ((back adj side) or	USPĀT;	2003/12/05 14:35
l		back-side or backside).clm.	US-PGPUB;	
ļ		İ	EPO; JPO;	
Ī			DERWENT; IBM TDB	
	·		TDM IND	

-	99	(transducer\$1).ab. and ((recess or cavity) and etch\$3).clm.	USPAT; US-PGPUB;	2003/12/05 14:36
			EPO; JPO; DERWENT;	
			IBM_TDB	
-	215	(427/155).CCLS.	USPAT; US-PGPUB;	2003/12/13 13:05
			EPO; JPO;	
,			DERWENT; IBM TDB	
j -	318	(427/156).CCLS.	USPAT;	2003/12/13 13:06
			US-PGPUB;	,
			EPO; JPO; DERWENT;	
_	11	((427/154).CCLS.) and (Ge or Germanium)	IBM TDB USPAT;	2003/12/13 13:07
		((42)/134).comb.) and (de of Germanium)	US-PGPUB;	2003/12/13 13:07
			EPO; JPO; DERWENT;	
			IBM TDB	
-	413	(427/154).CCLS.	USPAT; US-PGPUB;	2003/12/13 13:07
			EPO; JPO;	
			DERWENT; IBM TDB	
-	17	(((12))100201) 01 ((12))100,100201) 01	USPAT;	2003/12/13 13:07
		((427/154).CCLS.)) and (Ge or Germanium)	US-PGPUB; EPO; JPO;	
			DERWENT;	
_	415	(MEMS or micromechanical or	IBM_TDB USPAT;	2003/12/13 13:10
	1	microelectromechanical or	US-PGPUB;	2003/12/13 13:10
		microstructure\$1) and (Ge or Germanium) and (protect\$3 adj (coating or layer or	EPO; JPO; DERWENT;	
		material or film))	IBM_TDB	
-	208	(MEMS or micromechanical or microelectromechanical or	USPAT; US-PGPUB;	2003/12/13 13:12
		microstructure\$1) and (protect\$3 adj	EPO; JPO;	
		(coating or layer or material or film)) and mask\$3.clm.	DERWENT; IBM TDB	
-	156	(MEMS or micromechanical or	USPAT;	2003/12/13 13:13
		microelectromechanical or microstructure\$1) and (protect\$3 adj	US-PGPUB; EPO; JPO;	
		(coating or layer or material or film))	DERWENT;	
_	523	and (SOI or silicon-on-insulator) (MEMS or micromechanical or	IBM_TDB USPAT;	2003/12/13 14:44
		microelectromechanical or	US-PGPUB;	2003/12/13 14.44
		microstructure\$1) and (protect\$3 adj (coating or layer or material or	EPO; JPO; DERWENT;	
		film)).clm. and (pattern\$3 or etch\$3 or	IBM_TDB	
_	62	remov\$3 or form\$3).clm. (MEMS or micromechanical or	USPAT;	2003/12/13 13:31
		microelectromechanical or	US-PGPUB;	
		microstructure\$1).ti. and (protect\$3 adj (coating or layer or material or	EPO; JPO; DERWENT;	
		film)).clm. and (pattern\$3 or etch\$3 or	IBM_TDB	
_	0	remov\$3 or form\$3).clm. (MEMS or micromechanical or	USPAT;	2003/12/13 13:53
		microelectromechanical or	US-PGPUB;	
		microstructure\$1).ti. and (release adj mask).clm. and (pattern\$3 or etch\$3 or	EPO; JPO; DERWENT;	
_	283	remov\$3 or form\$3).clm. (MEMS or micromechanical or	IBM_TDB	
	233	microelectromechanical or	USPAT; US-PGPUB;	2003/12/13 13:47
		microstructure\$1) and (protective adj layer).clm.	EPO; JPO;	
			DERWENT; IBM TDB	
-	4	(("5627317") or ("5574222")).PN.	USPĀT; US-PGPUB;	2003/12/13 13:47
			EPO; JPO;	
			DERWENT; IBM TDB	
	·		TOU IND	

-	89	(germanium with mask).clm.	USPAT;	2003/12/13 13:55
			US-PGPUB;	•
	i		EPO; JPO;	
			DERWENT;	Į i
_	62	(MEMS or micromechanical or	IBM_TDB	
	02	microelectromechanical or	USPAT;	2003/12/13 14:50
1		microstructure\$1) and ((pattern\$3 or	US-PGPUB;	
		etch\$3 or remov\$3 or form\$3) with	EPO; JPO;	
		(backside or back-side)).clm.	DERWENT;	
-	102		IBM_TDB USPAT;	2003/12/13 14:51
1	102	((pattern\$3 or etch\$3 or remov\$3 or	US-PGPUB;	2003/12/13 14:51
		form\$3) with (backside or back-side)).clm.	EPO; JPO;	i
1	1	Total (backside of back-side)).Cim.	DERWENT;	
	1		IBM TDB	
-	898	257/419	USPAT;	2003/12/13 15:07
			US-PGPUB;	2003/12/13 15:07
			EPO; JPO;	1
	1		DERWENT;	
			IBM TDB	
j -	215	((MEMS or micromechanical or	USPĀT;	2004/01/11 17:23
	l	microelectromechanical or	US-PGPUB;	2004/01/11 17.23
-		microstructure\$1) and (protective or	EPO; JPO;	
1		sacrificial) and (mask\$3 or oxide or	DERWENT;	1
		polysilicon)).clm.	IBM TDB	
-	15		USPAT;	2004/01/11 17:25
		or ("5326726") or ("5343064") or	US-PGPUB;	
		("5747353") or ("5506175") or	EPO; JPO;	
		("5576250")).PN.	DERWENT;	
			IBM_TDB	
-	33	((216/2).CCLS.) and (MEMS).ab.	USPAT;	2004/01/11 17:37
	1		US-PGPUB;	
			EPO; JPO;	
1			DERWENT;	1
_	114	(/216/2) CCI () MDVC	IBM_TDB	
	114	((216/2).CCLS.) and MEMS	USPAT;	2004/01/11 17:38
			US-PGPUB;	l i
		8	EPO; JPO;	1
į į	i		DERWENT; IBM TDB	
-	8783	MEMS	USPAT;	2004/01/11 17:48
			US-PGPUB;	2004/01/11 17:48
		•	EPO; JPO;	
			DERWENT;	
			IBM TDB	
-	4380	MEMS and etch\$3	USPAT;	2004/01/11 17:49
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM TDB	
-	1098		USPAT;	2004/01/12 09:09
'		sacrificial or mask\$3 or protect\$3).clm.	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
_ 1		OZDAG 1	IBM_TDB	
-	57	(MEMS and etch\$3 and (release or	USPAT;	2004/01/11 17:51
1		sacrificial or mask\$3 or protect\$3).clm.)	US-PGPUB;	
İ	l	and (backside or back-side or (back adj	EPO; JPO;	
Į		side)).clm.	DERWENT;	
			IBM TDB	